

Poster Session 3

MAR 8 (Tue), 13:00-14:30

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P3-087A-LN

Bandgap and Microstructural Engineering of InGaN for Solar Photovoltaic Applications

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Thermal Chemical Vapor Deposition Growth of In-Doped ZnO Nanowire for Dye-Sensitized Solar Cell Fabrication

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Using the Inductively Coupled Plasma Assisted Hot-wire CVD to Fabricate the HIT Solar Cells

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P3-090A-LN

Use of Inductively-Coupled Discharged HMDSO Plasma to Deposit Barrier Layer Onto Poly (Lactic Acid) Film

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P3-091A-LN

Etching Characteristics of Magnetic Tunnel Junction Materials in CH₃OH Inductively Coupled Plasma

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- P3-092A-LN **Impact of Low Pressure Direct Current Plasma Discharge on Etch Rate of Silicon Dioxide Single Crystals**
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- P3-093A-LN **UV Curing of Photoresist for MEMS Processes**
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- P3-096A-LN **Characteristics of Low-*k* SiOC(-H) Ultra Thin Films Deposited by Using PAALD**
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- P3-097C-LN **Mechanical Properties of a-C:H/Si Films Deposited by PCVD**
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